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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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In re Patent Application of)
Kenji KASAHARA et al.)
Serial No. 09/640,521)
Filed: August 17, 2000)
For: LASER APPARATUS AND)
LASER ANNEALING METHOD)

Art Unit: 1725
Examiner: G. Evans

CERTIFICATE OF MAILING

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AMENDMENT

Honorable Commissioner of Patents
Washington, D.C. 20231

Sir:

In response to the Office Action dated July 2, 2002 please amend the above-identified
application as follows:

IN THE CLAIMS:

Please amend claims 4-6, 9, 12, 15, 18, 21, 24, 27, and 30-32 as follows:

4. (Amended) A laser apparatus, comprising:
- a laser source for emitting a laser light;
 - a half mirror for dividing the laser light into a first laser light and a second laser light;
 - an optical system for guiding the first laser light and the second laser light onto a top surface and a back surface of an object to be treated, respectively,
 - wherein the optical system includes a filter for attenuating the first laser light,
 - a substrate holder for holding a substrate,
 - wherein a semiconductor film is formed over the substrate.

5. (Amended) A laser apparatus, comprising:
- a laser source for emitting a laser light;
 - a half mirror for dividing the laser light into a first laser light and a second laser light;